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Modeling Direct Ink Write for Filled Silicones

Presented by:

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Team members:

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Weston Ortiz (UNM)

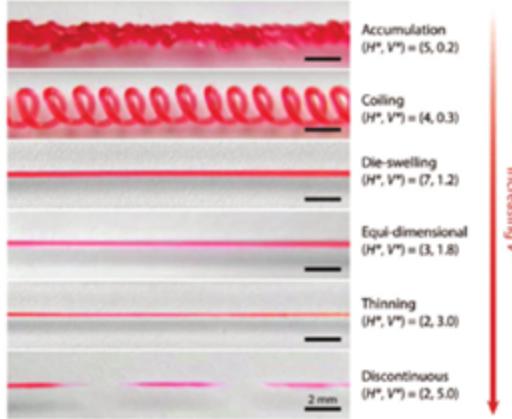
Society of Rheology Annual Meeting
Austin, Texas
October 13-17th, 2024

SAND2024-????

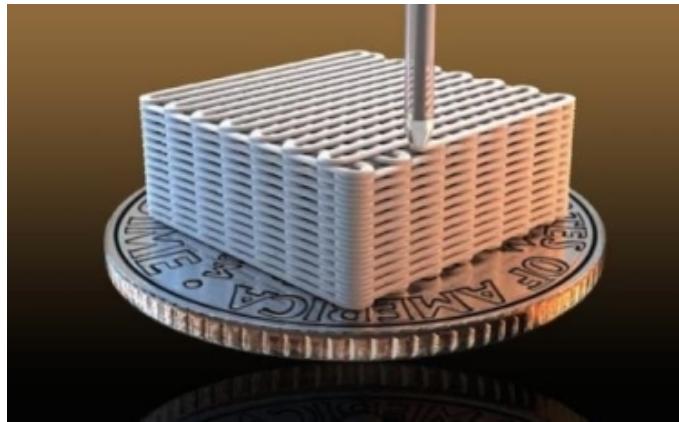
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Examples of Direct Ink Write



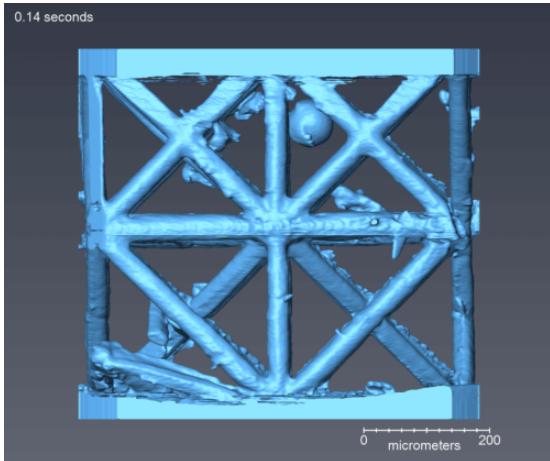
Bioink printability
Zhang et al, 2018



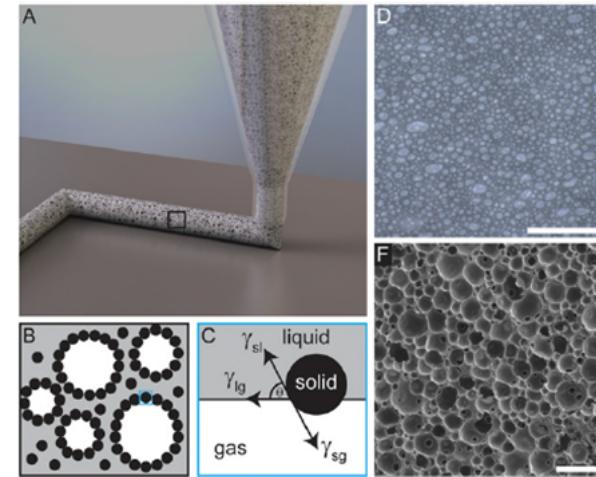
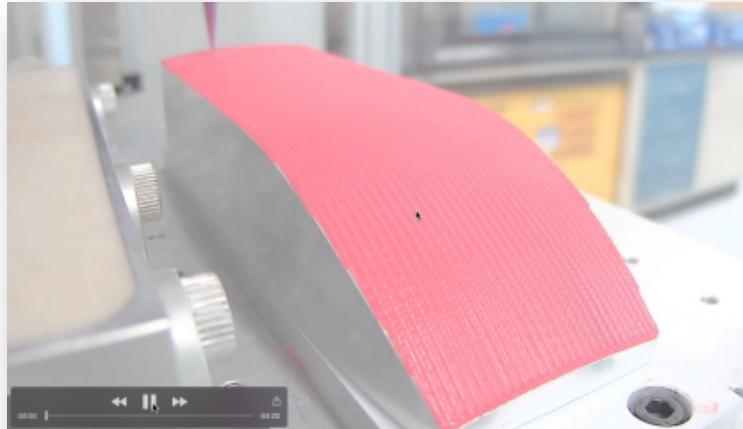
Graphene aerogel microlattices
Ryan Chen (LLNL)



Printing an Ear
www.think3d.in/researchers-use-biobot-3d-bioprinter-for-nerve-cell-engineering



Silicone Engineered Foam
Adam Cook (SNL)



Direct Foam Writing
Muth et al., 2017

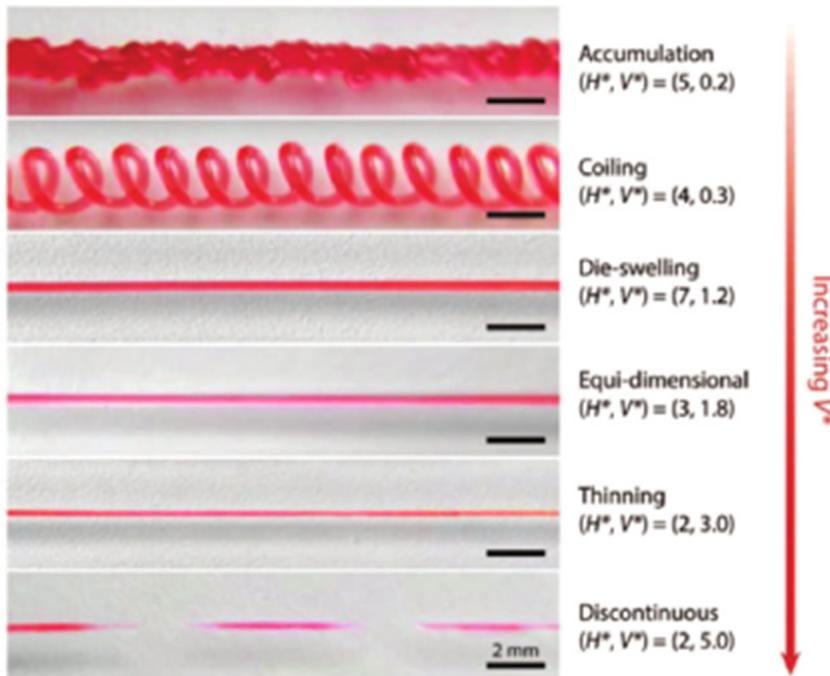


Possible Defects in 3D Printing

Manufacturing Defects can effect quality of printed parts

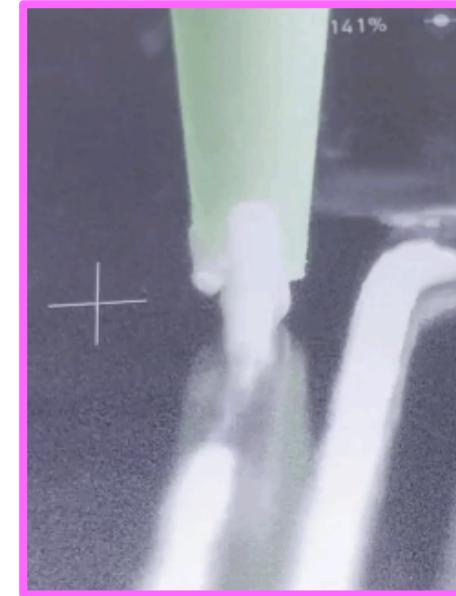
Examples include

- Coiling defects
- Line discontinuities
- Strut variability
- Clogging by aggregates
- Material sagging during or after printing



Bioink printability
Zhang et al, 2018

56vol% CaCO_3



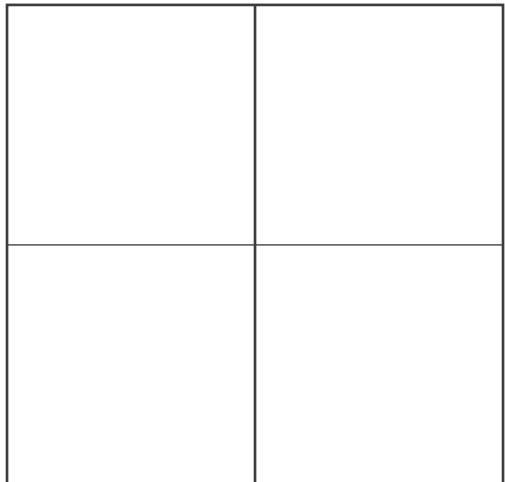
56vol% Melamine



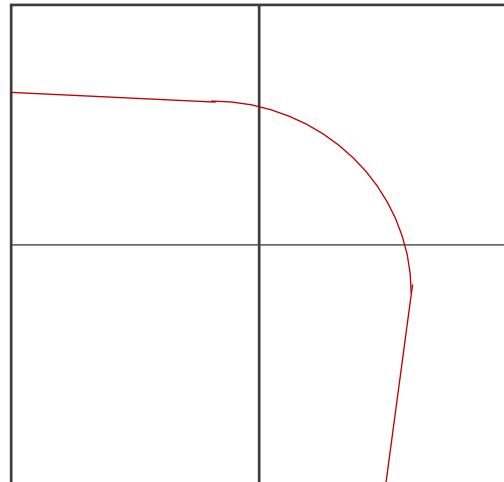
Modeling and simulation can be used to reduce defects in printed part, design/optimize/troubleshoot production problems, inform physics-based process controllers, and predict operating windows.

Level Set and CDFEM for Direct Ink Write

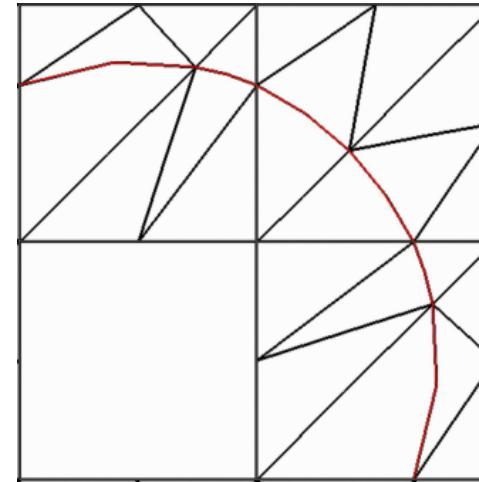
CDFEM Uses Ideas From XFEM, Level Set Methods, and ALE Moving Mesh



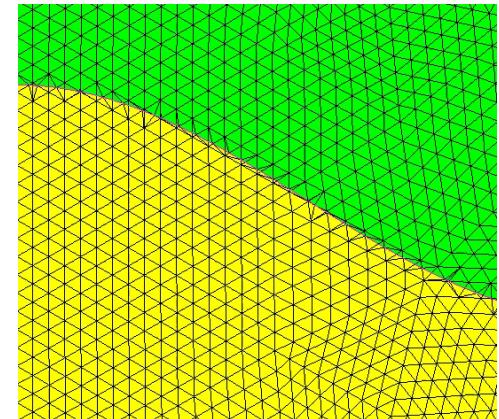
Base mesh



Level Set Function



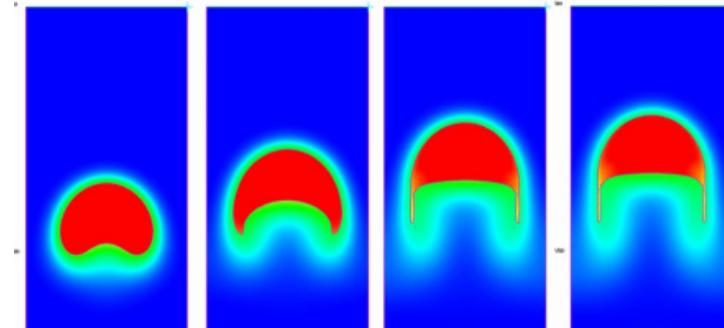
CDFEM



Benefits: Meshed free surface allows for easy application of boundary conditions, discontinuous variables are straight forward, topological changes

Drawbacks: Mass loss similar to diffuse interface methods, expensive, file bloat, solver issues

New Krino adaptive mesh capabilities allows for flexible load balancing across many processors in parallel, decreasing run times and memory usage, and improving robustness.



Governing Equations

Conservation Equations

$$\nabla \cdot \mathbf{u} = 0$$

$$\rho \left(\frac{\partial \mathbf{u}}{\partial t} + (\mathbf{u} \cdot \nabla) \mathbf{u} \right) = -\nabla p + \nabla \cdot (\mu (\nabla \mathbf{u} + \nabla \mathbf{u}^T))$$

$$\rho C_p \left(\frac{\partial T}{\partial t} + \mathbf{u} \cdot \nabla T \right) - \nabla \cdot (k \nabla T) = \dot{q}$$

Level Set Equation

$$\frac{\partial \phi}{\partial t} + (\mathbf{u} \cdot \nabla) \phi = 0$$

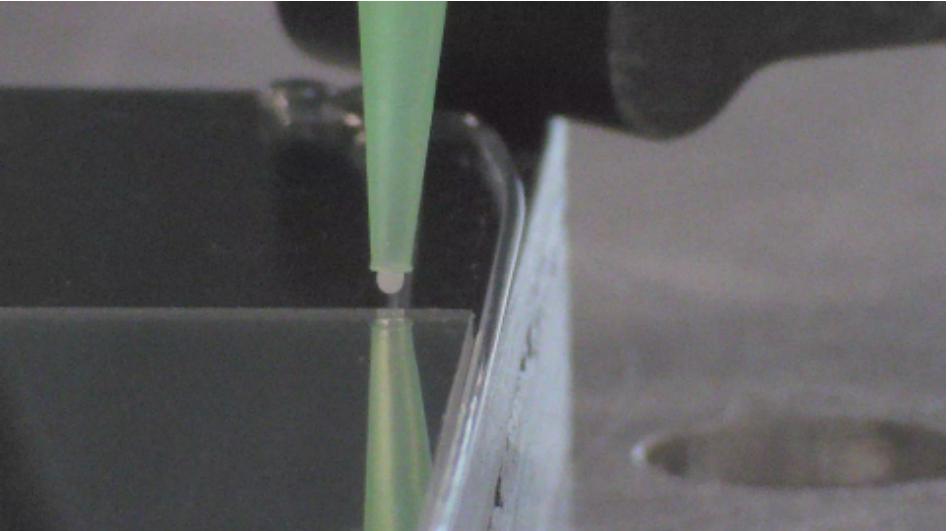
Interface Boundary Conditions

$$[\mathbf{u}]_\Delta = 0, \quad \mathbf{x} \in \Gamma_F$$

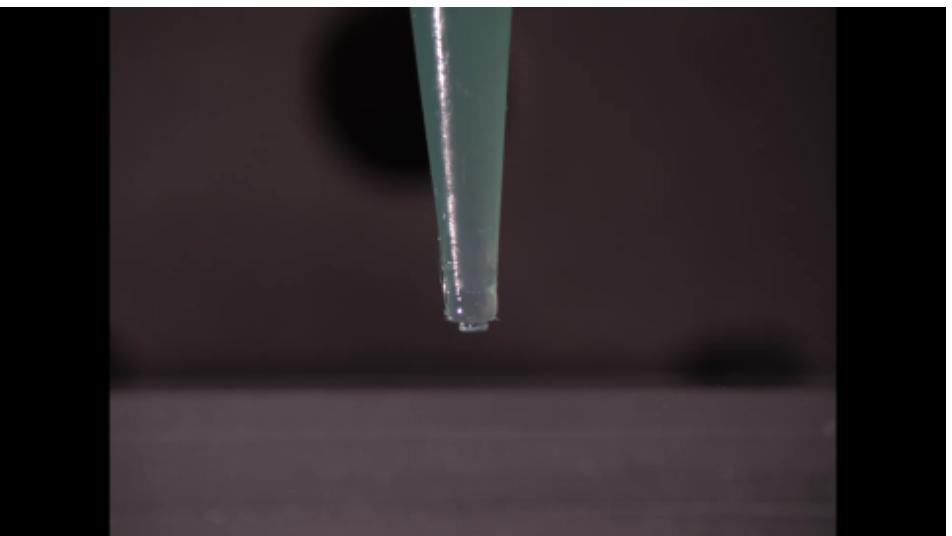
$$[-p\mathbf{I} + \mu(\mathbf{x}) (\nabla \mathbf{u} + \nabla \mathbf{u}^T)]_\Delta \cdot \hat{\mathbf{n}} = -\gamma \kappa \hat{\mathbf{n}}, \quad \mathbf{x} \in \Gamma_F$$

Validation Experiments

Serpentine Printing Pattern

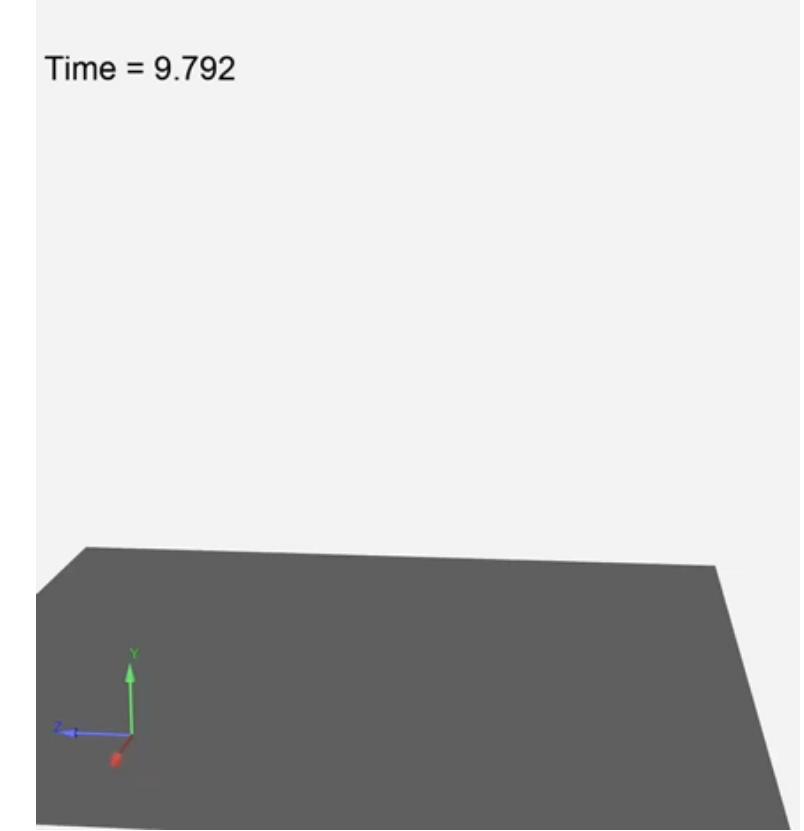
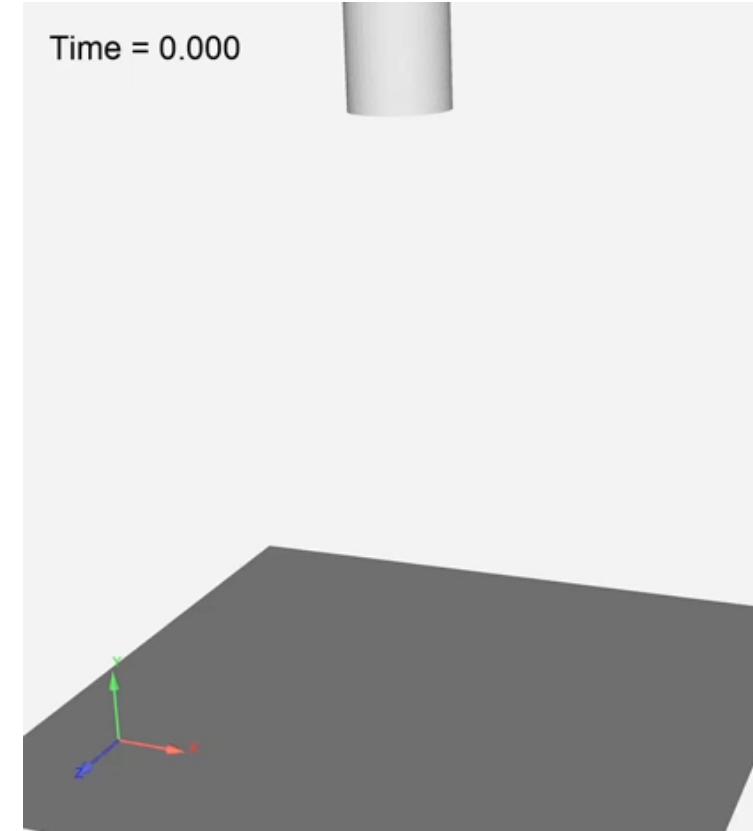
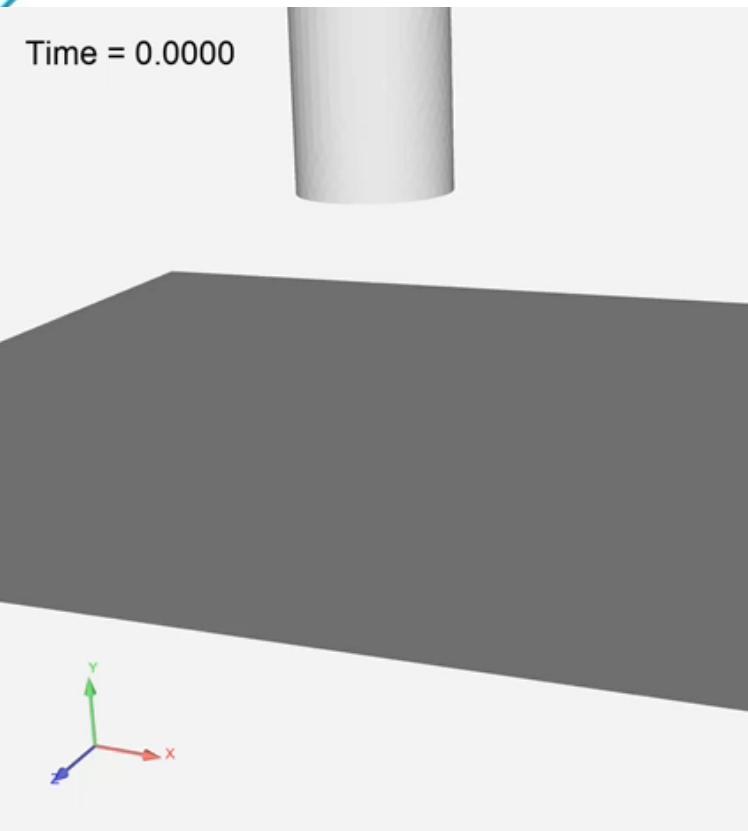


Stationary Drop



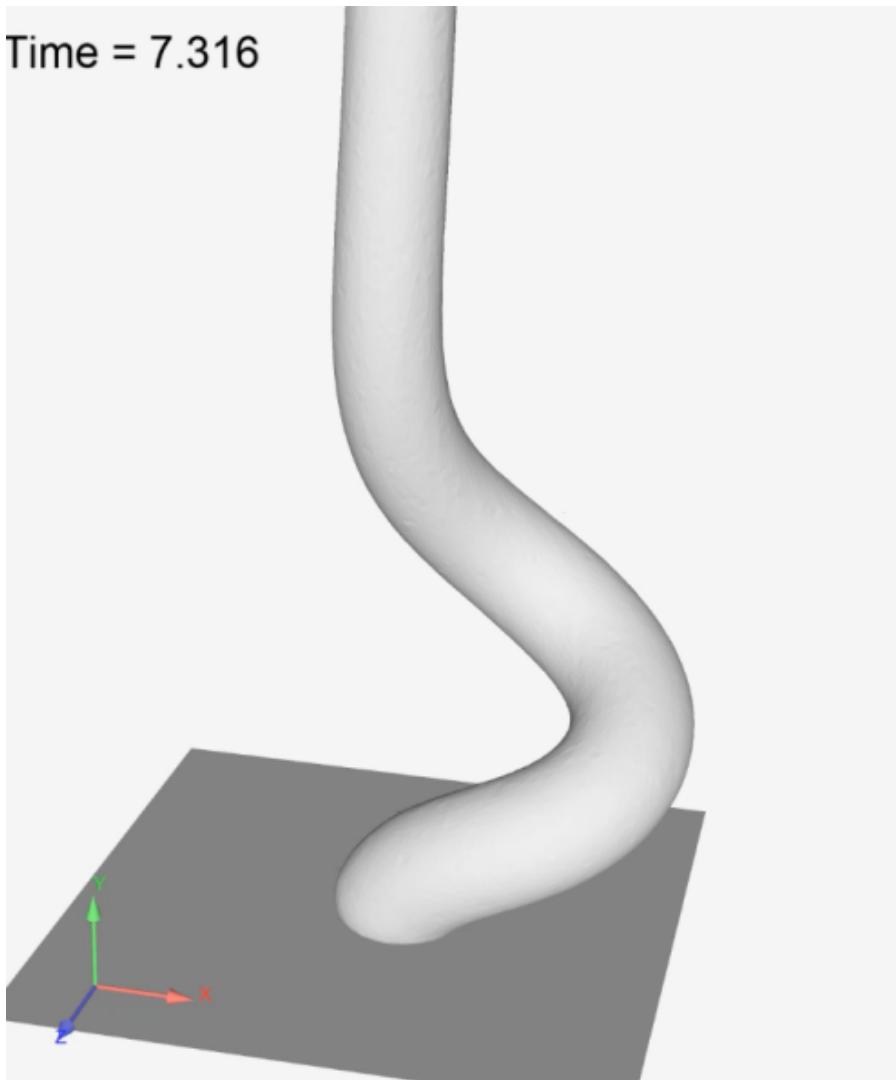
Printer designed by Adam Cook & Derek Reinholtz

Stability of Print Related to Height of Nozzle: Stationary Plate

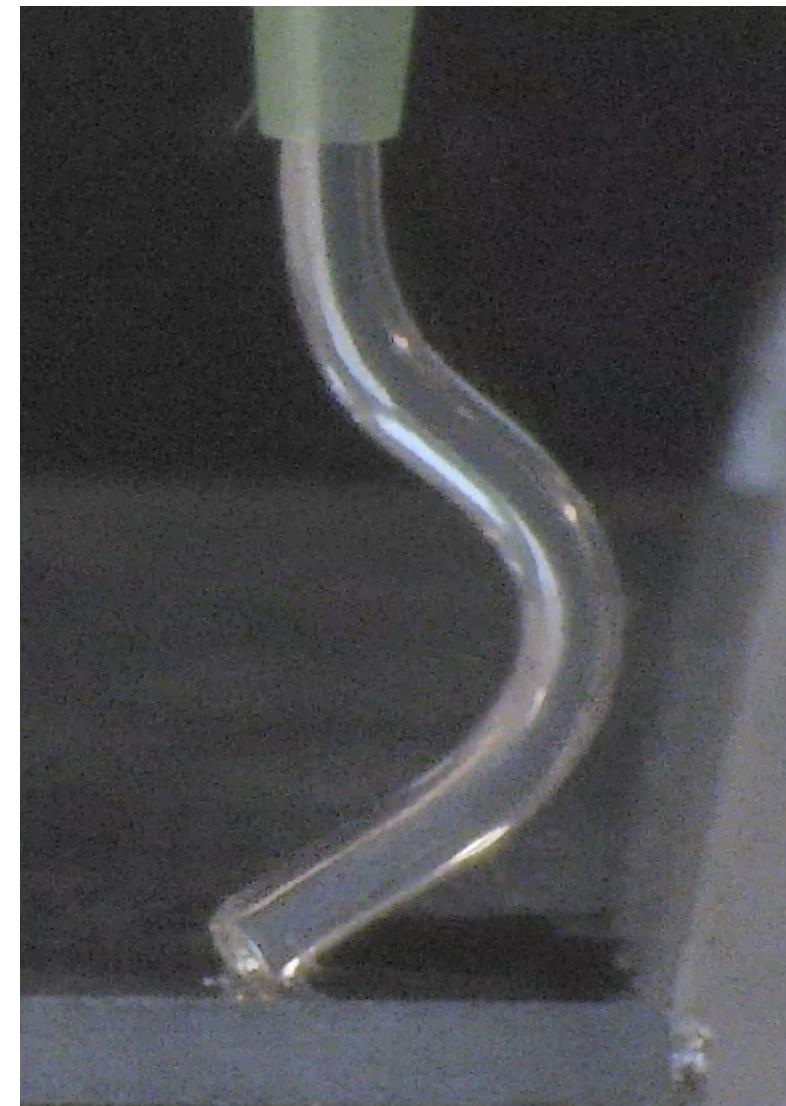


Probability of Coiling Instability Increases with Nozzle Height

Time = 7.316

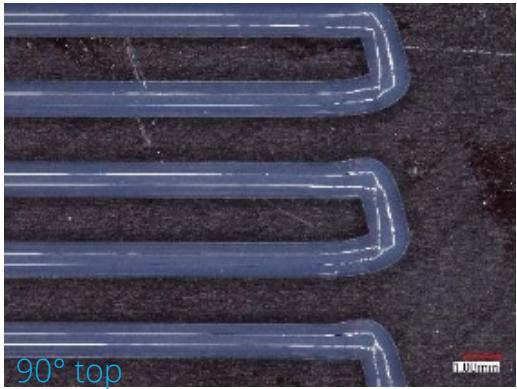


Newtonian with 10mm Nozzle Height

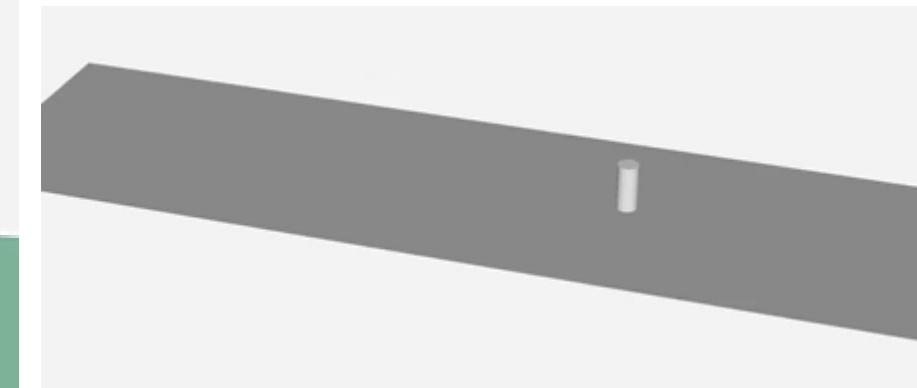
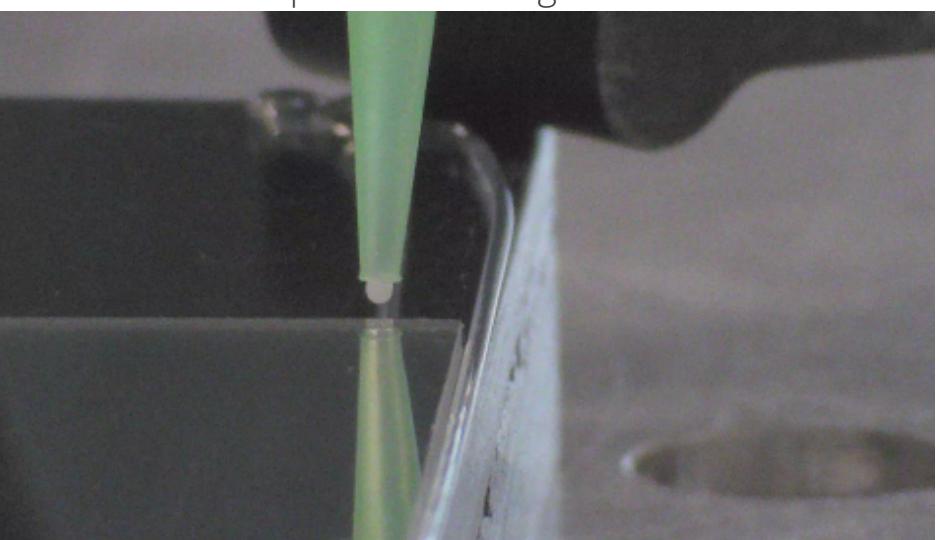


Alec Kucala, Jess Kopatz, Anne Grillet, Rekha Rao

CDFEM Model with Adaptive Refinement: Newtonian Model



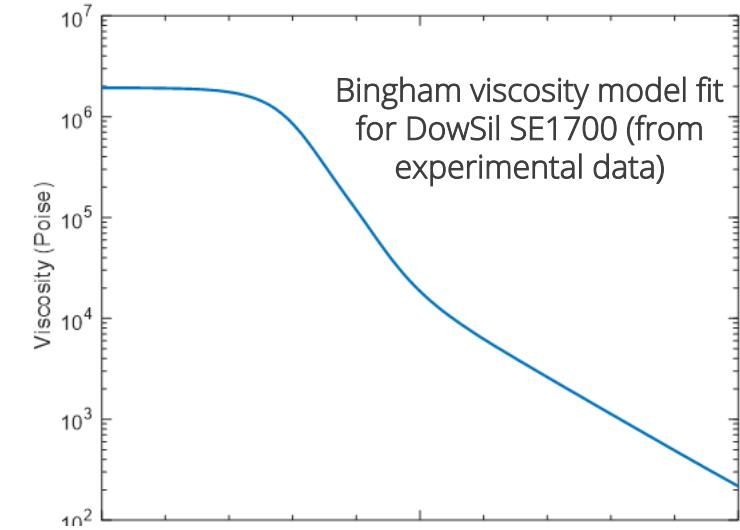
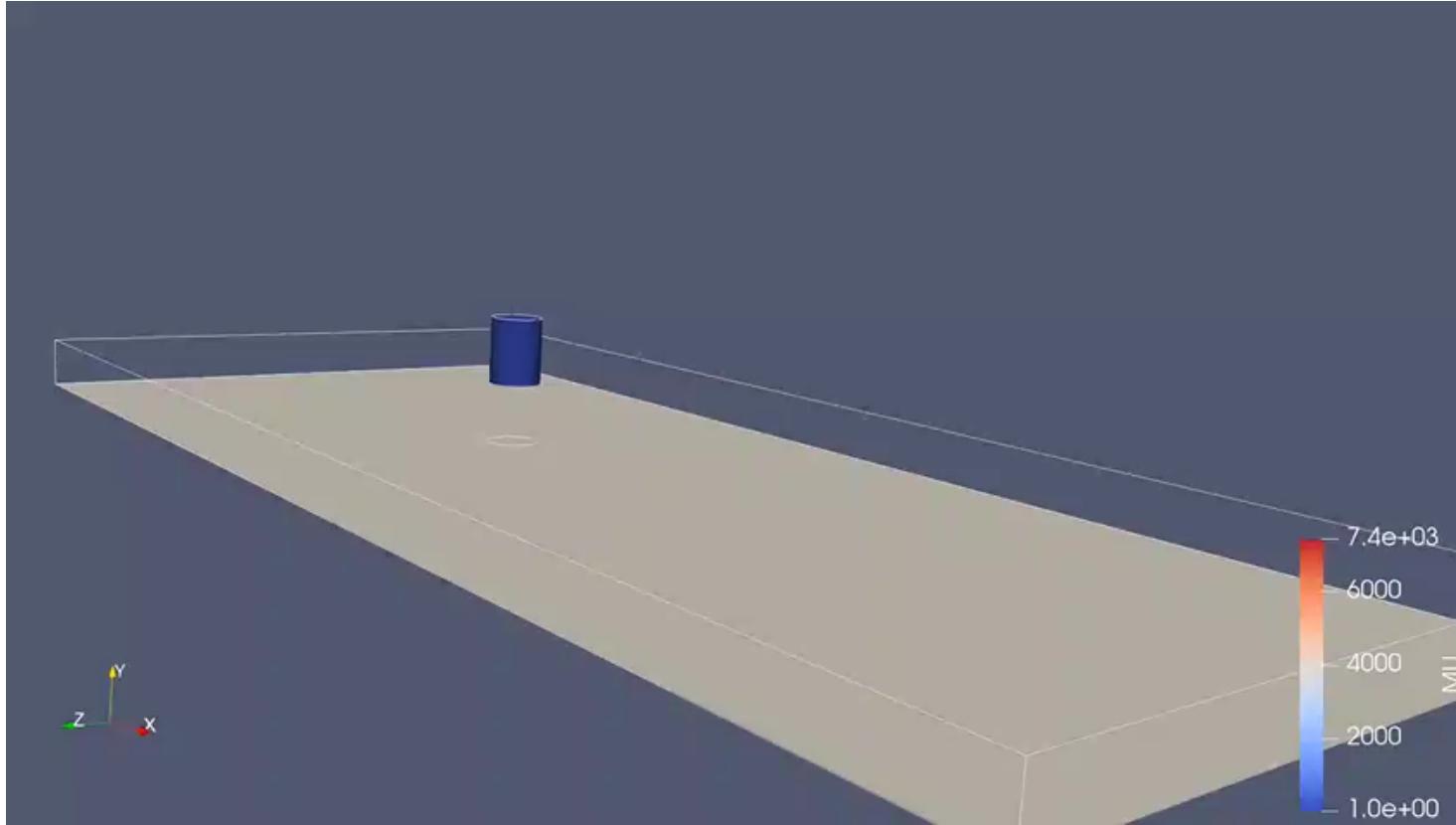
CDFEM Model with adaptive mesh refinement shows good mass conservation



Increasing substrate speed can lead to defects



Including Complex Rheology: Yield Stress Models



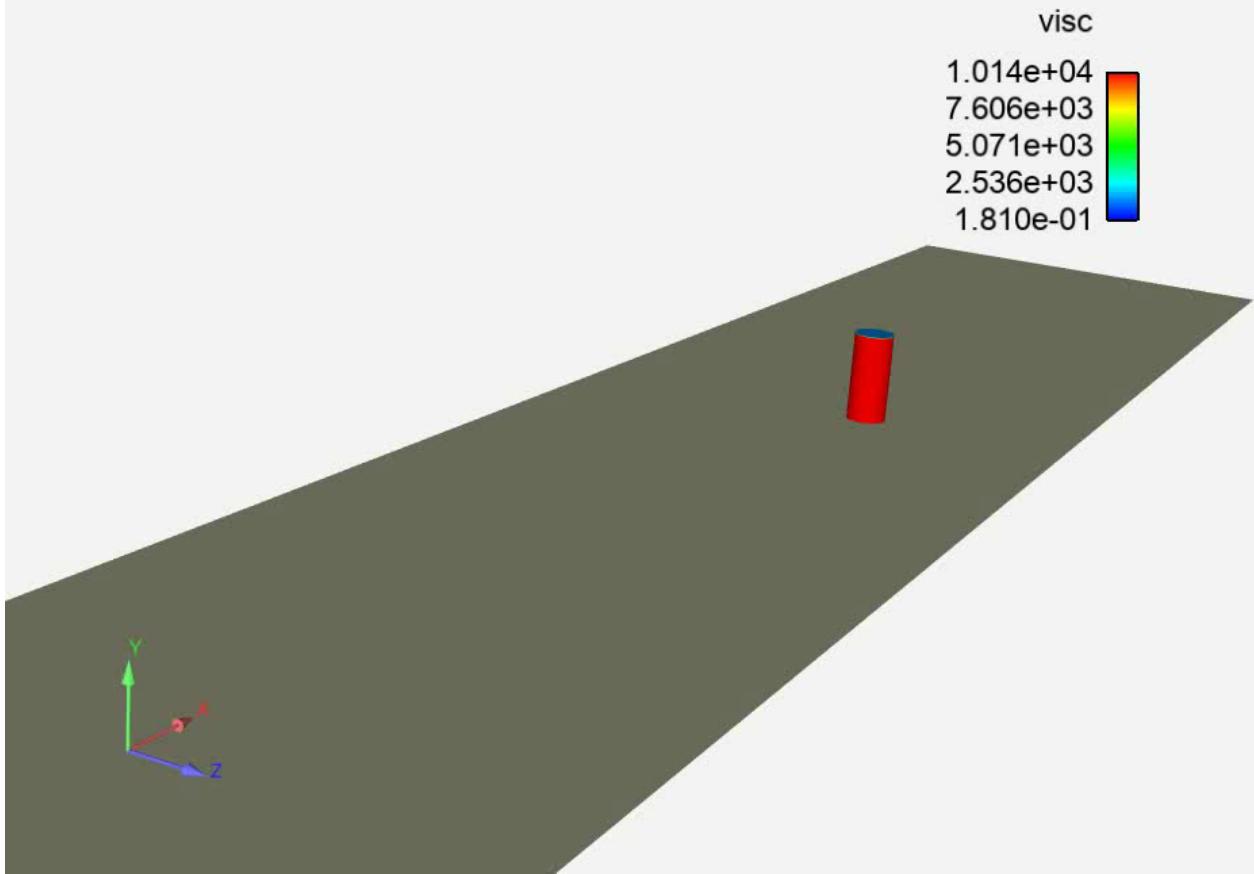
$$\mu(\dot{\gamma}) = \mu_\infty + \left(\mu_0 - \mu_\infty + \tau_y \frac{1 - e^{-\dot{\gamma}F}}{\dot{\gamma}} \right) (1 + (\lambda \dot{\gamma})^a)^{\frac{n-1}{a}}$$



| Variable | Value |
|--------------|-------------|
| μ_0 | 29740 Poise |
| μ_∞ | 10 Poise |
| τ_y | 9520 Barye |
| λ | 7.542 |
| F | 200 |
| a | 2.764 |
| n | 0.633586 |

Casson Model Including Yield Stress

Time = 0.000



Level set method with Casson Model and realistic viscosity model but less yield stress



Level set method with higher viscosity shows instability after the corner

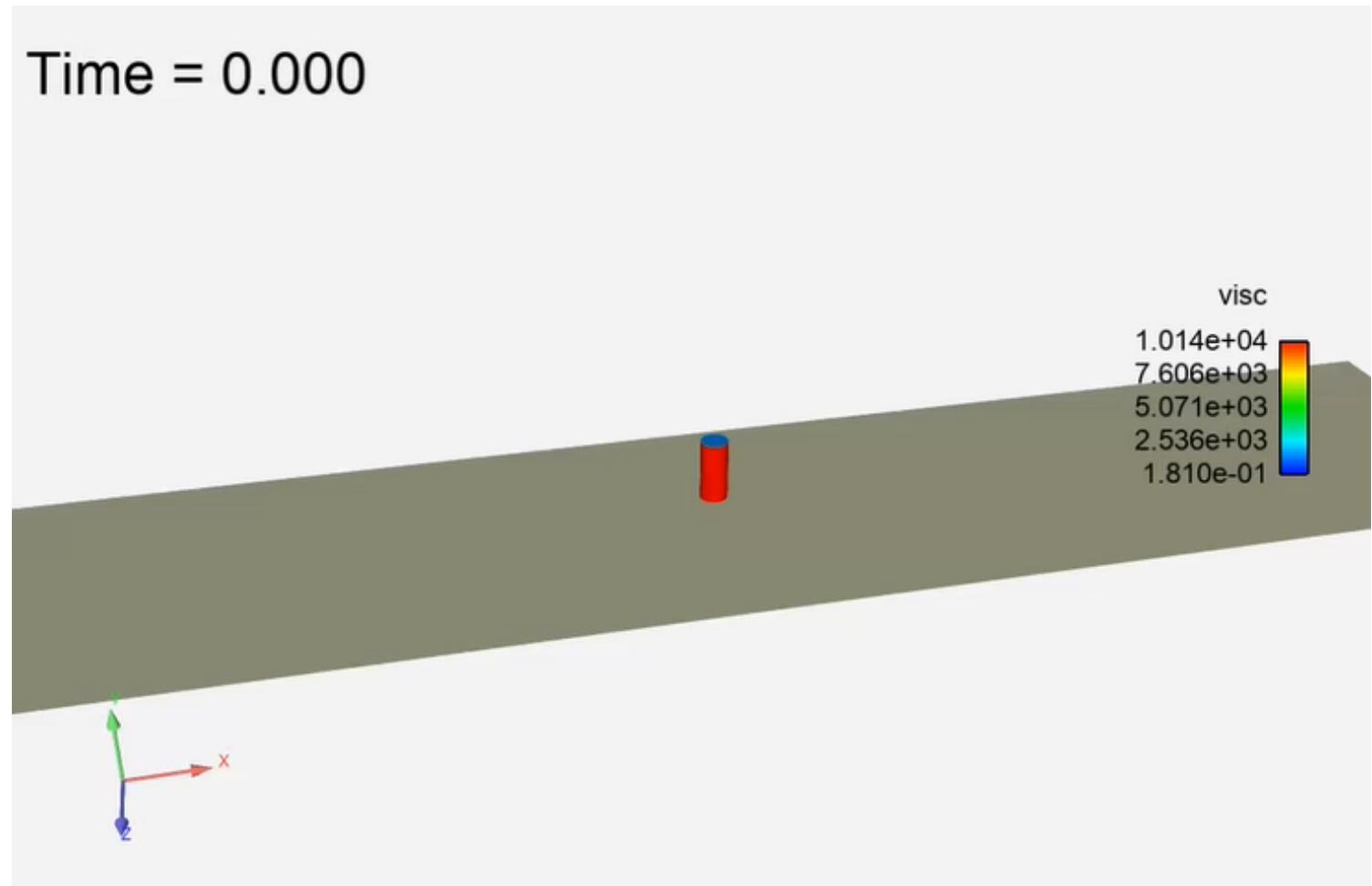
$$\mu(\gamma) = \left[\sqrt{\mu_0} + \sqrt{\frac{\tau_y}{\gamma}} (1 - e^{-\sqrt{\frac{m\gamma}{\tau_{ref}}}}) \right]^2$$

| Casson Model | |
|-----------------------|------------|
| μ_0 | 136.4 Pa-s |
| τ_y | 926.4 Pa |
| shear_ref | 11/s |
| m | 20 |
| $m/\text{shear_ref}$ | 20 |

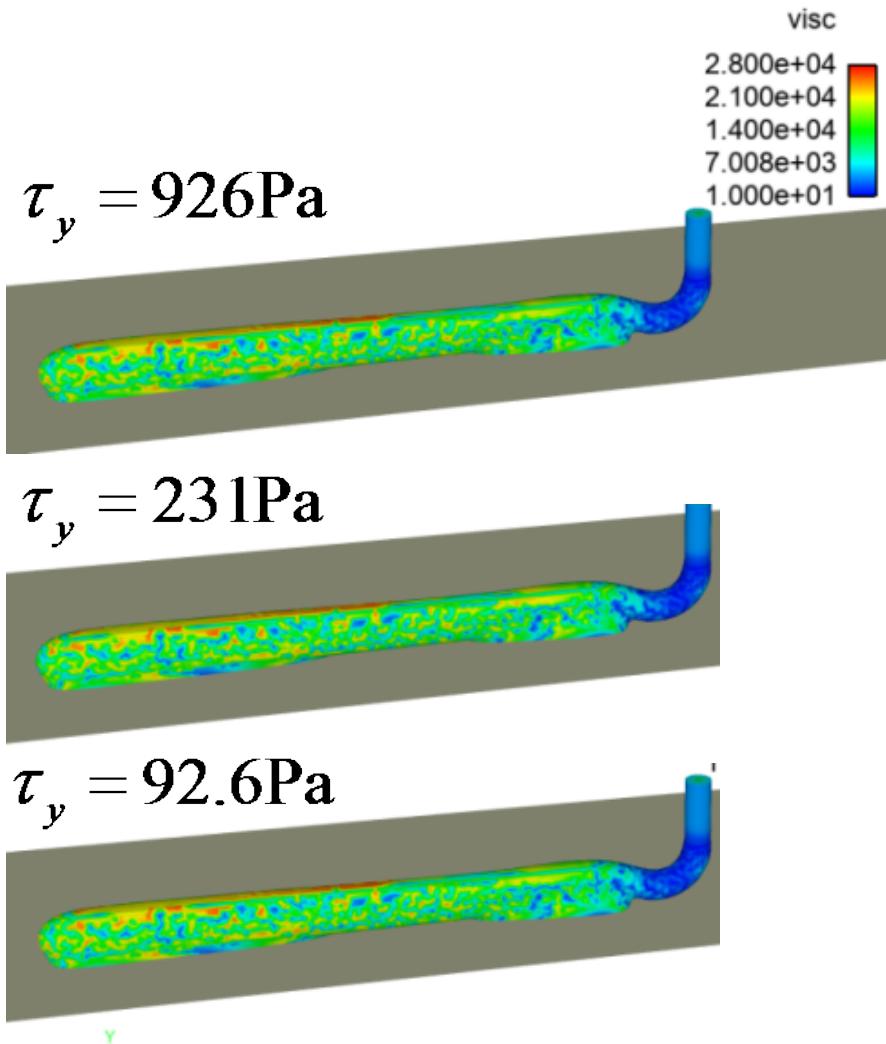
Two-Layer Study of Casson Yield Stress

Movie showing multi-layer deposition of a yield stress material in DIW printing.

- Rheology is presented as a Casson model which incorporates a yield stress and also shear thinning viscosity.
- The colors represent the viscosity of the fluid which drops when sheared (blue) and then resolidifies in the bead (red).



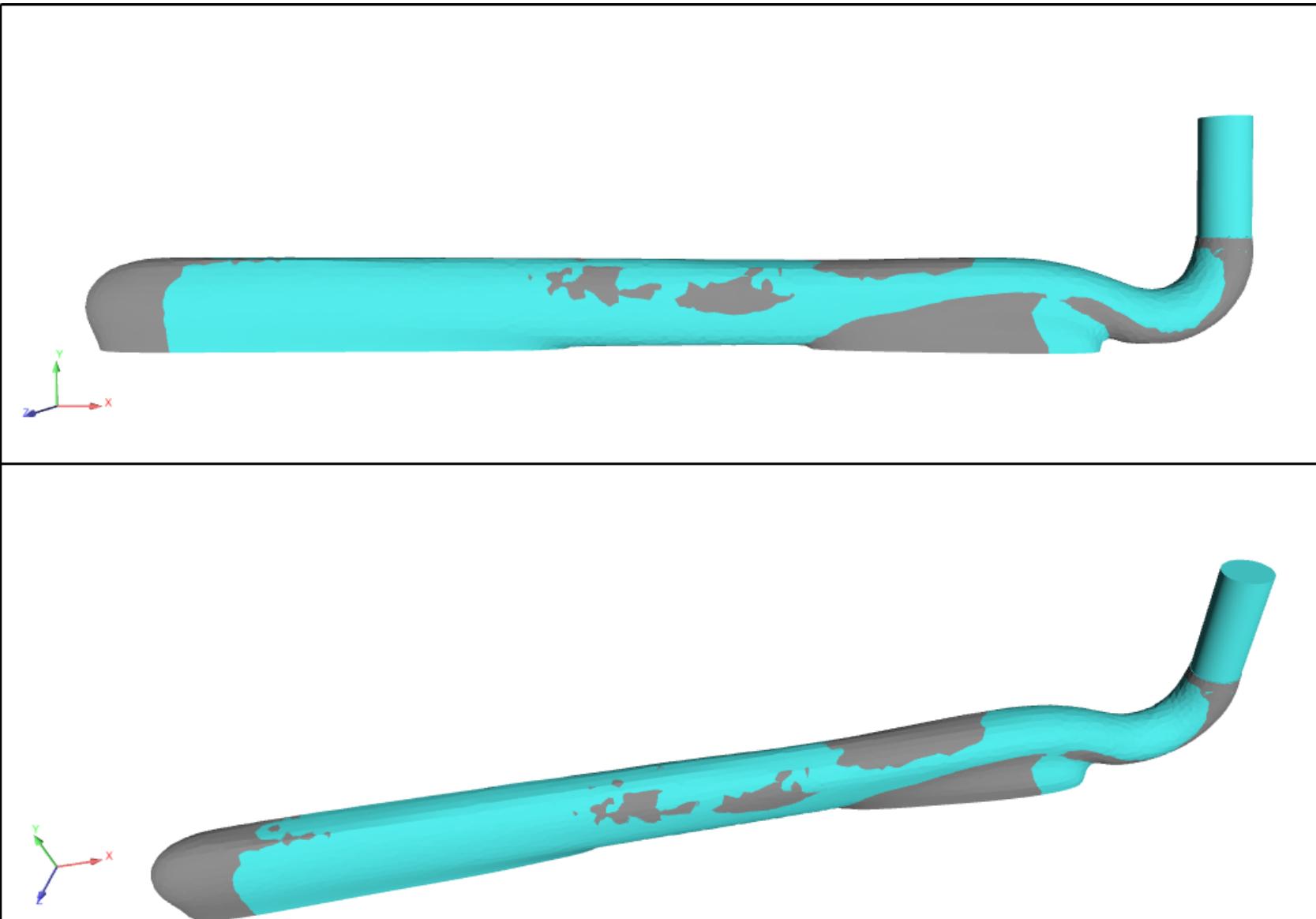
Sensitivity study for Casson Yield Stress



| Casson Model | |
|-----------------------|------------|
| μ_0 | 136.4 Pa-s |
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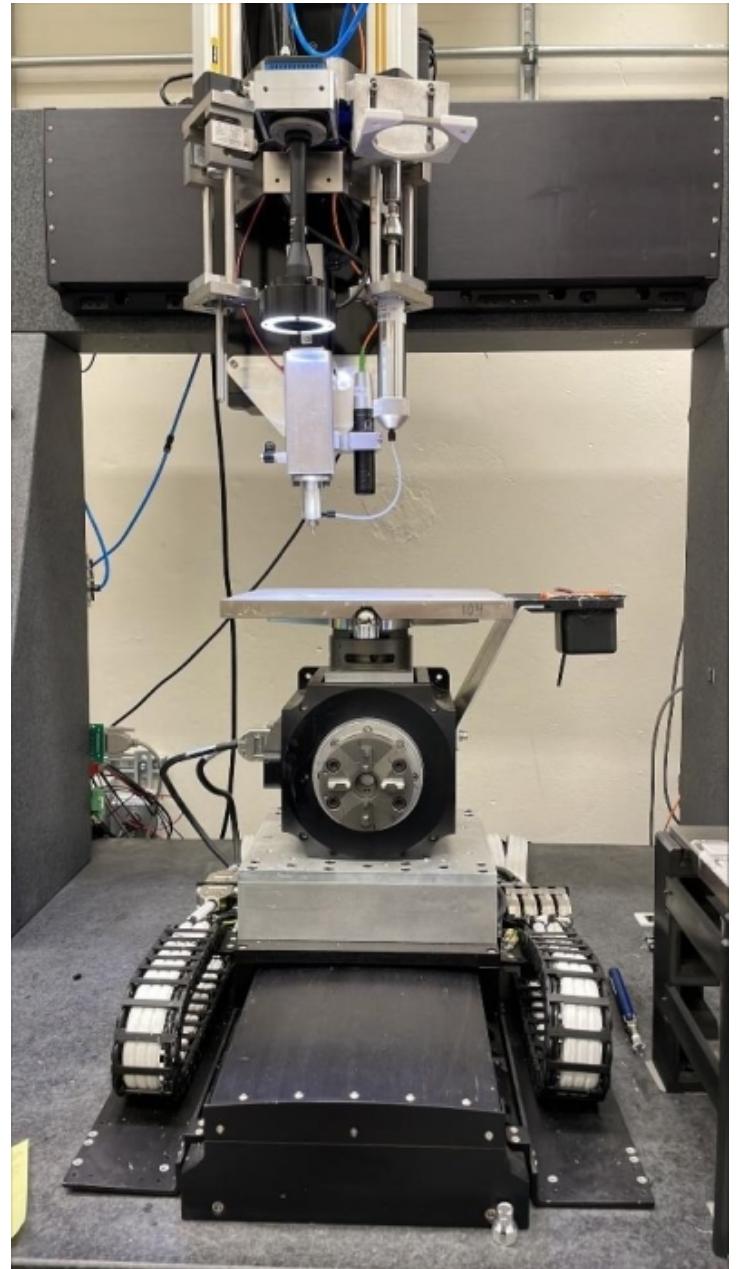
$$\mu(\gamma) = \left[\sqrt{\mu_0} + \sqrt{\frac{\tau_y}{\gamma}} \left(1 - e^{-\sqrt{\frac{m\gamma}{\gamma_{ref}}}} \right) \right]^2$$

Sensitivity study for Casson Yield Stress: Two Viewing Angles



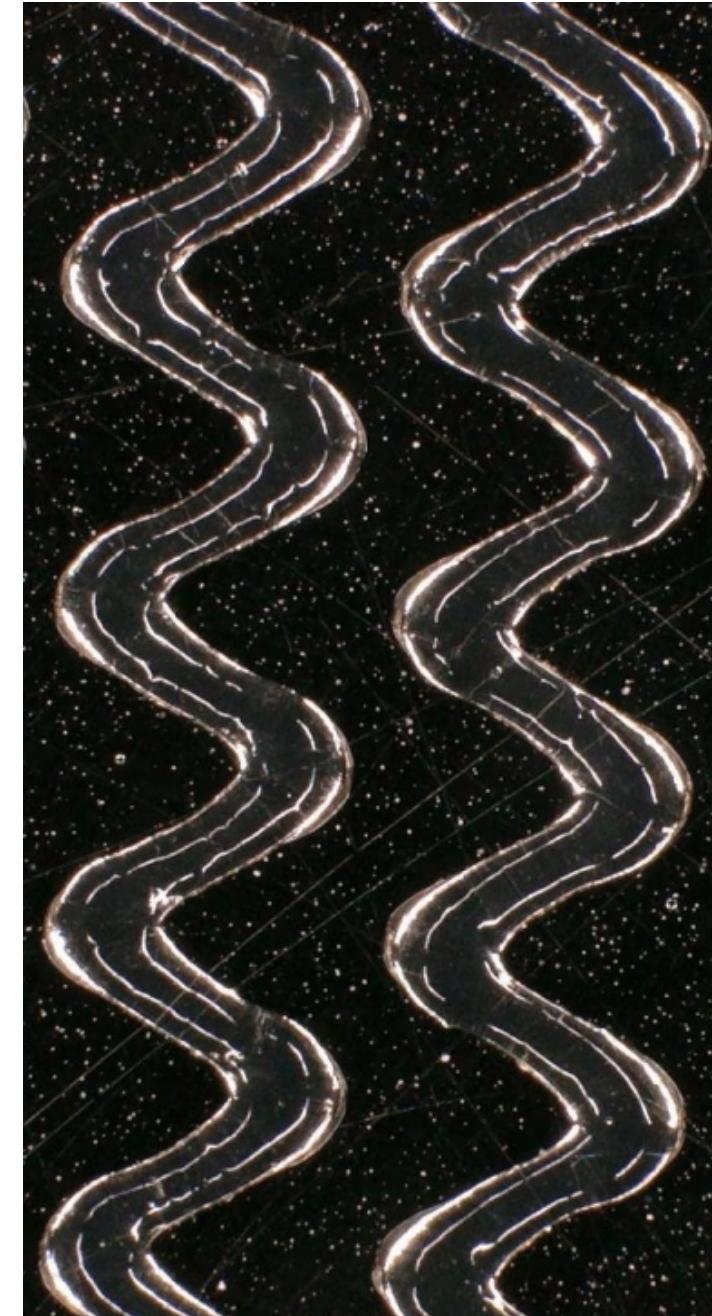
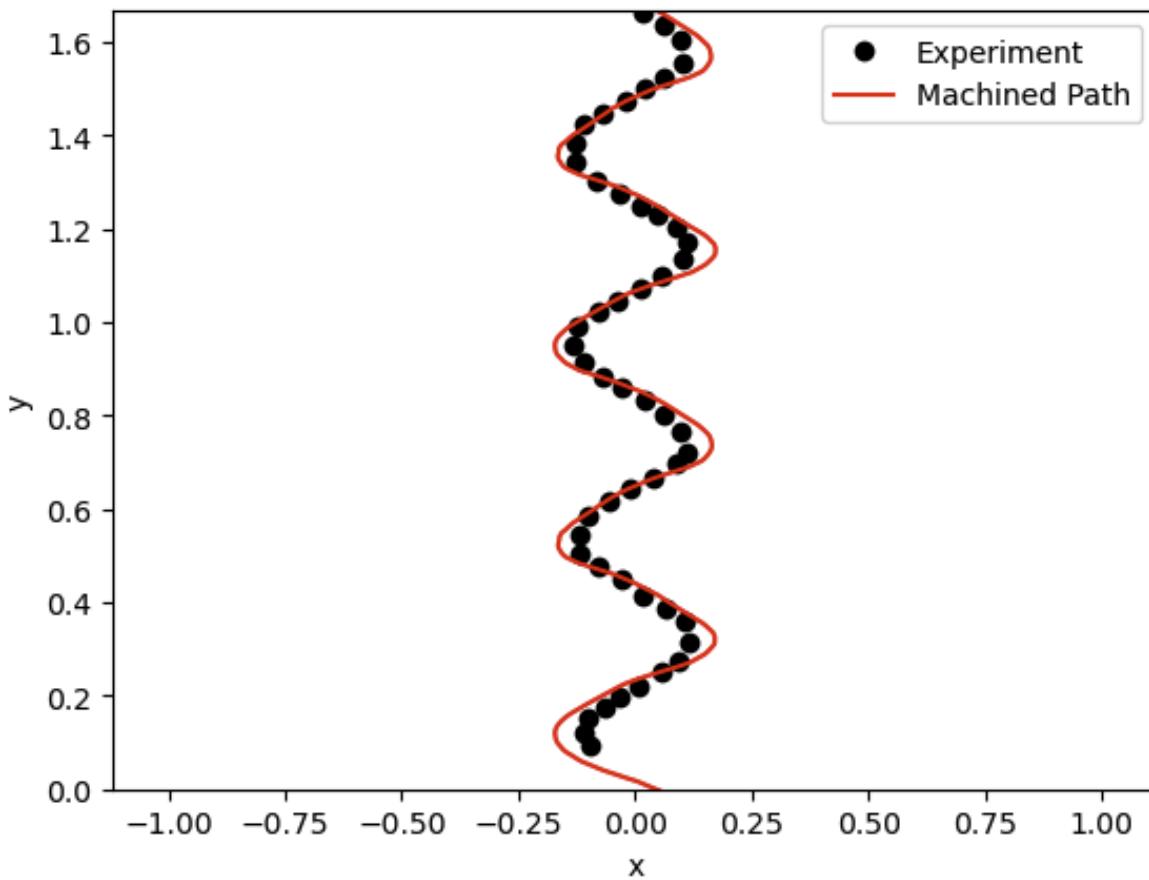
New work -Sinusoidal printing pattern

- Print sinusoidal pattern on substrate at specified amplitude and period
- Nozzle moves in the x-z (in-plane) direction
- Substrate can move in y-direction (normal to syringe movement plane)
- Uses silicone as the printing material
- Desirable to match amplitude and period of machined path
- Currently, errors in the printing amplitude are present

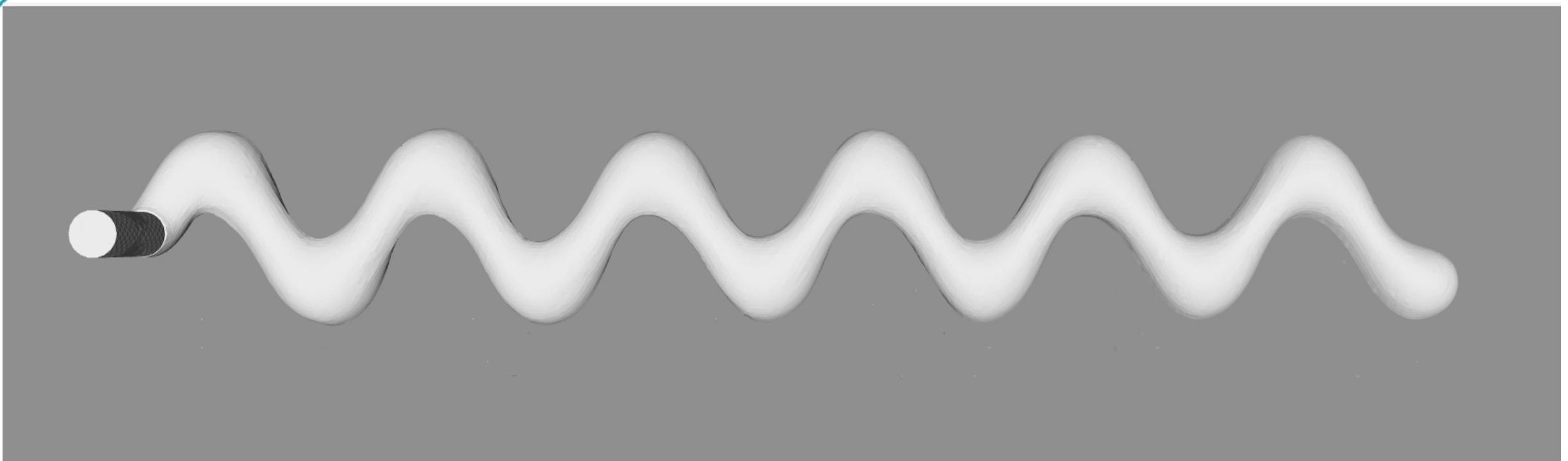


Experimental result

- Top-down view of experimental printing pattern
- Amplitude mismatch between experiment and machined path.



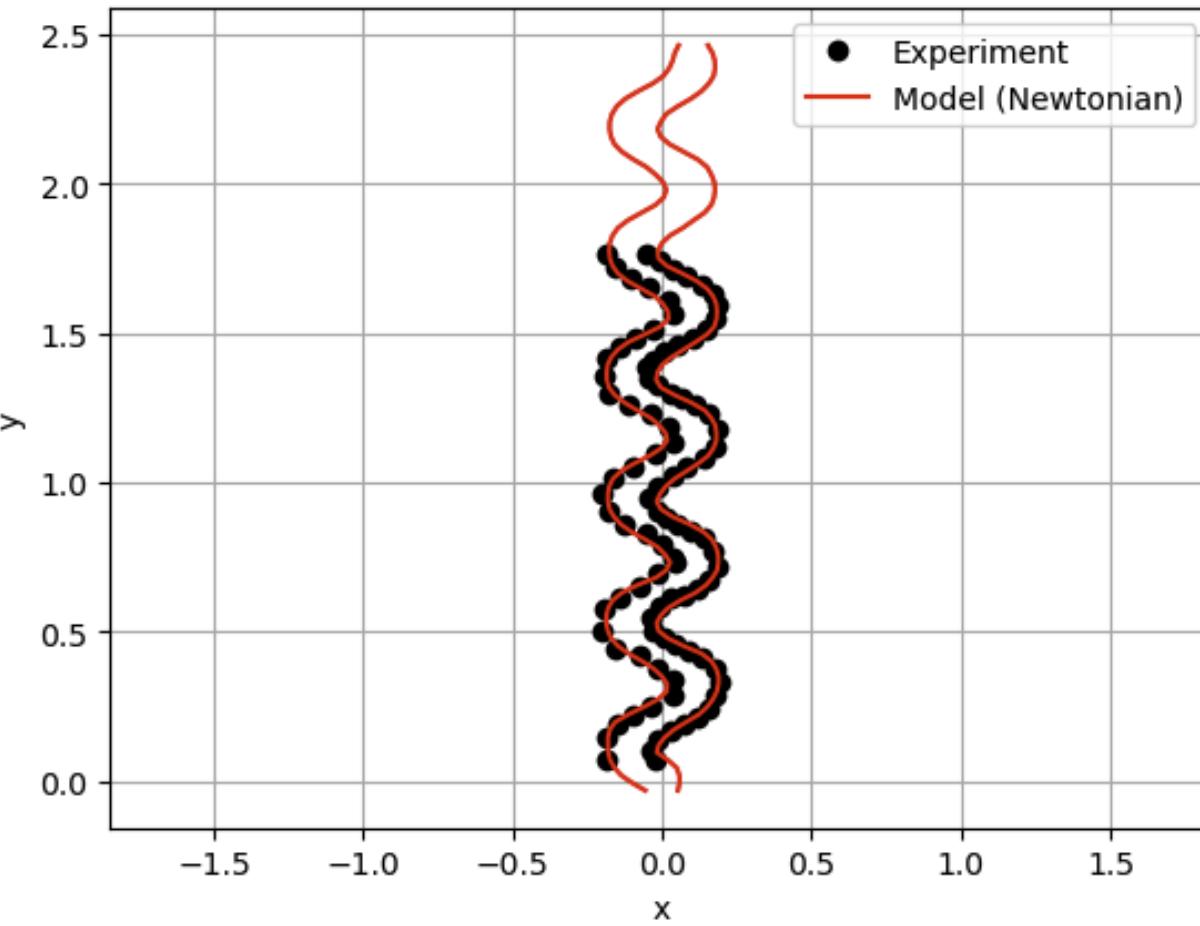
Model result - Newtonian fluid



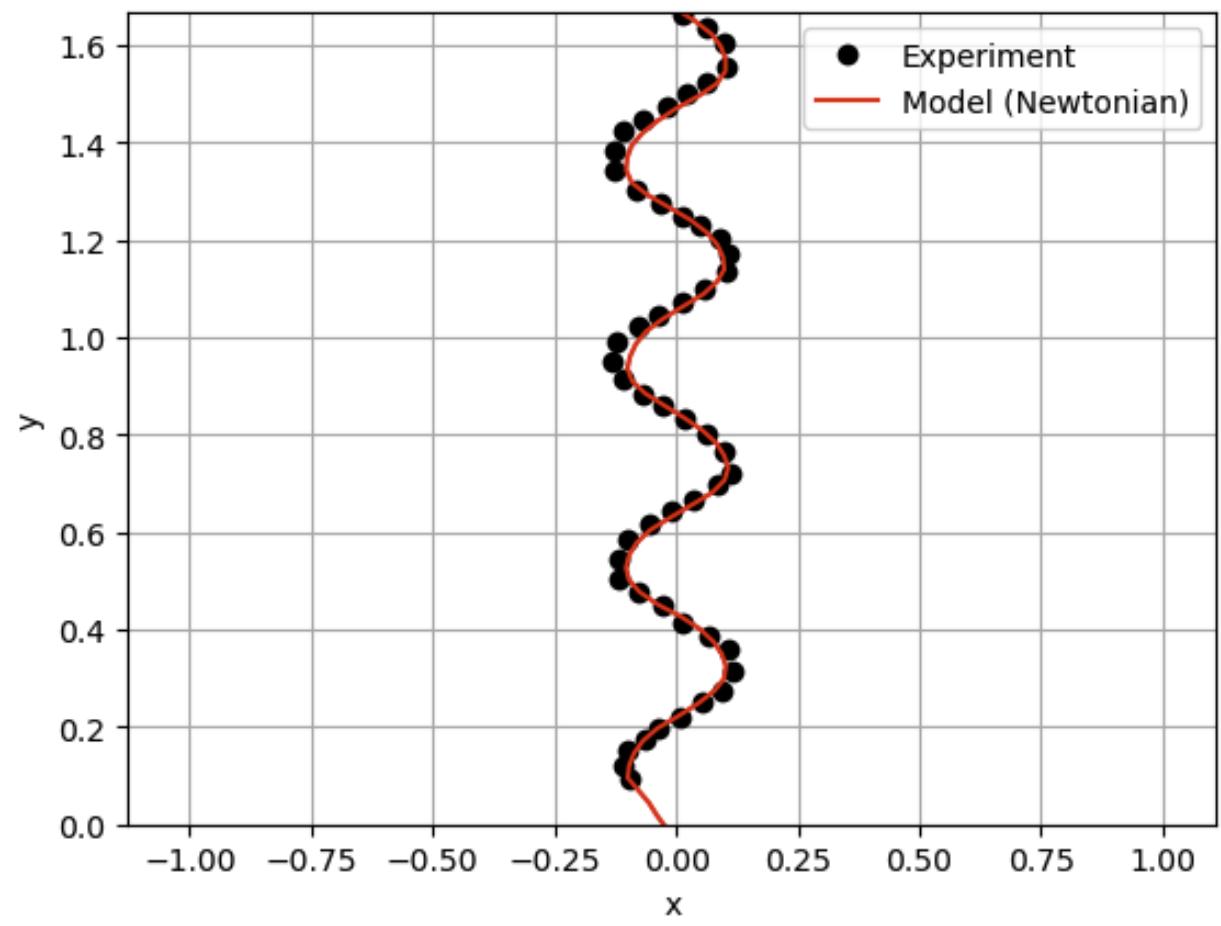
- Used the machine velocity data for substrate boundary conditions
- Printed sinusoidal pattern
- Newtonian fluid ($\mu = 1e5$ poise)

Sinusoidal pattern comparison - Newtonian

Model vs Experiment Path

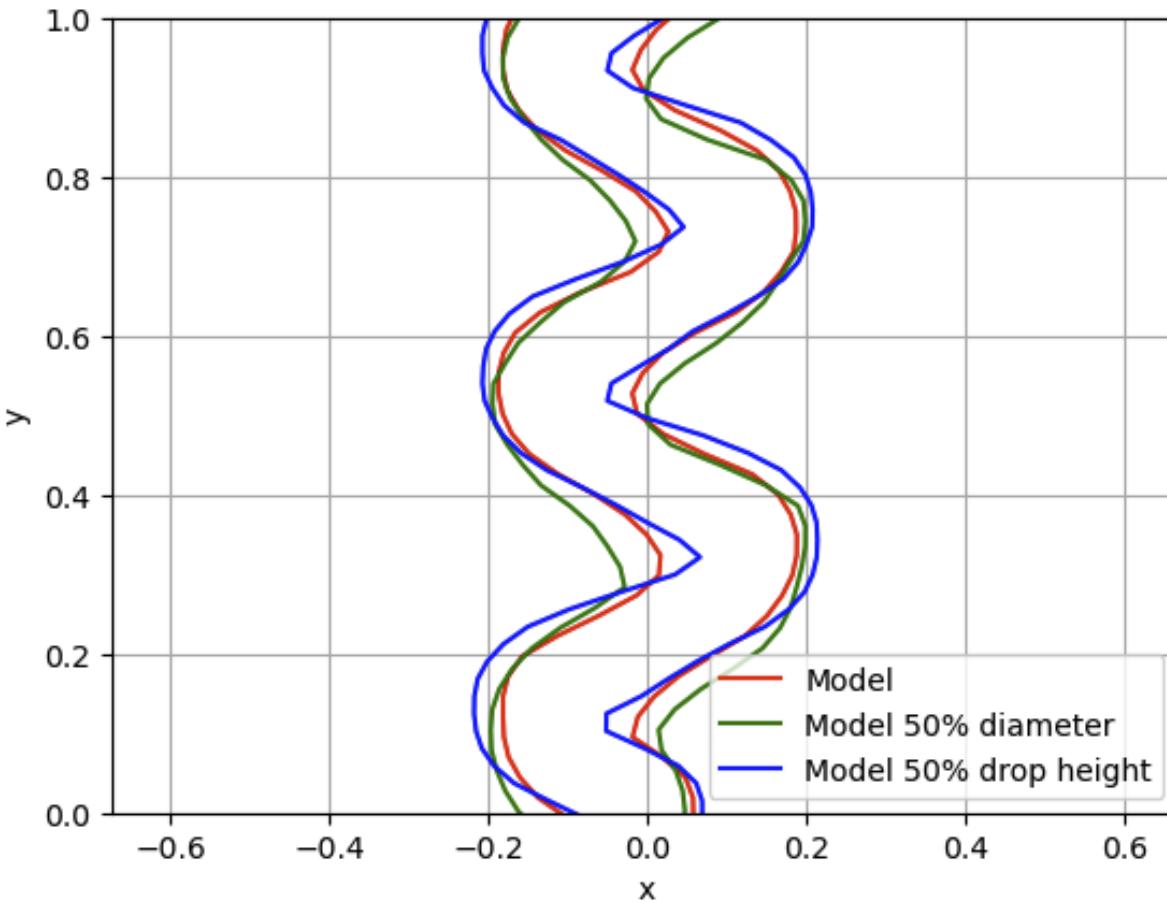


Model vs Experiment Mean Path

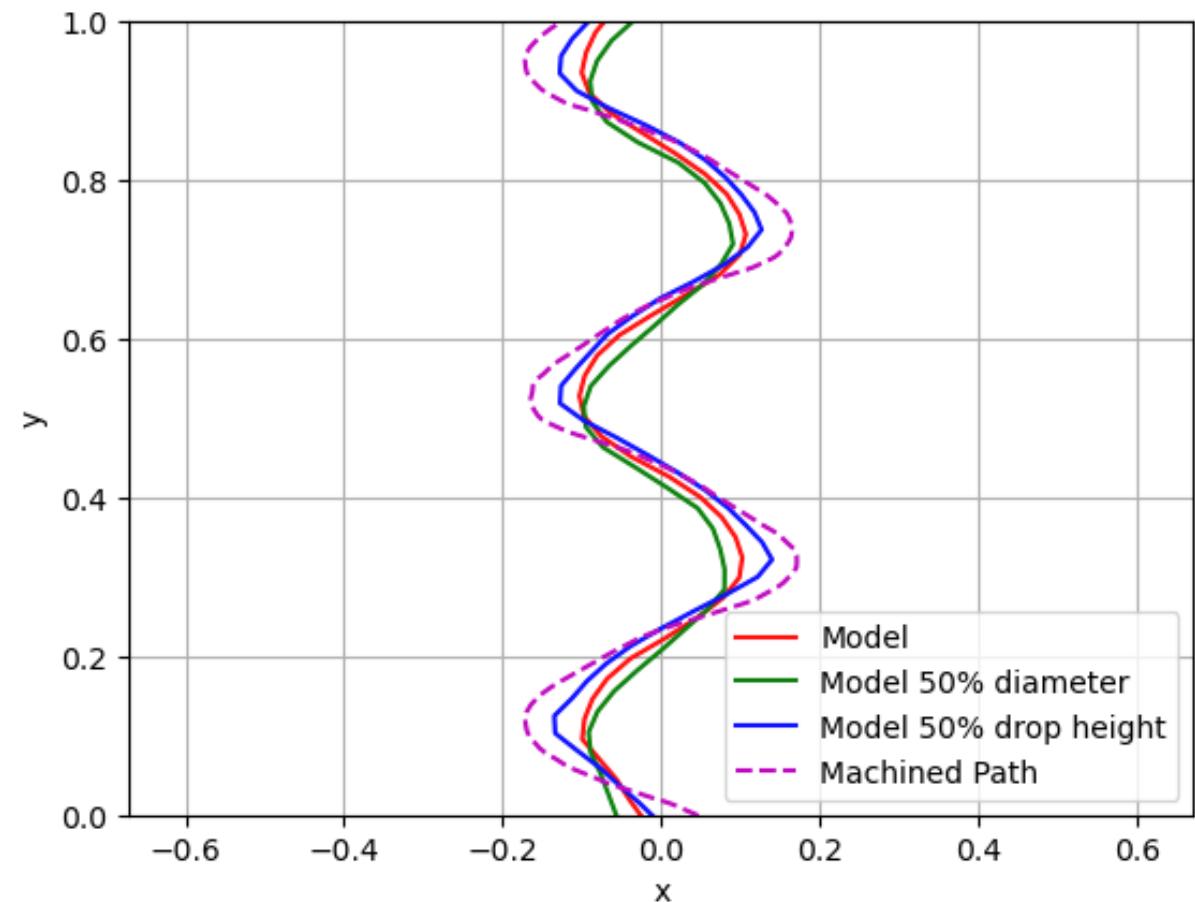


Parameterization of the drop height and diameter

- Alter the diameter of the nozzle and drop height
- Decreasing the drop height appears to increase the mean path amplitude closer to the machined path
- Decreasing nozzle diameter (while keeping flow rate constant) shrinks amplitude, but increases thickness of printed material



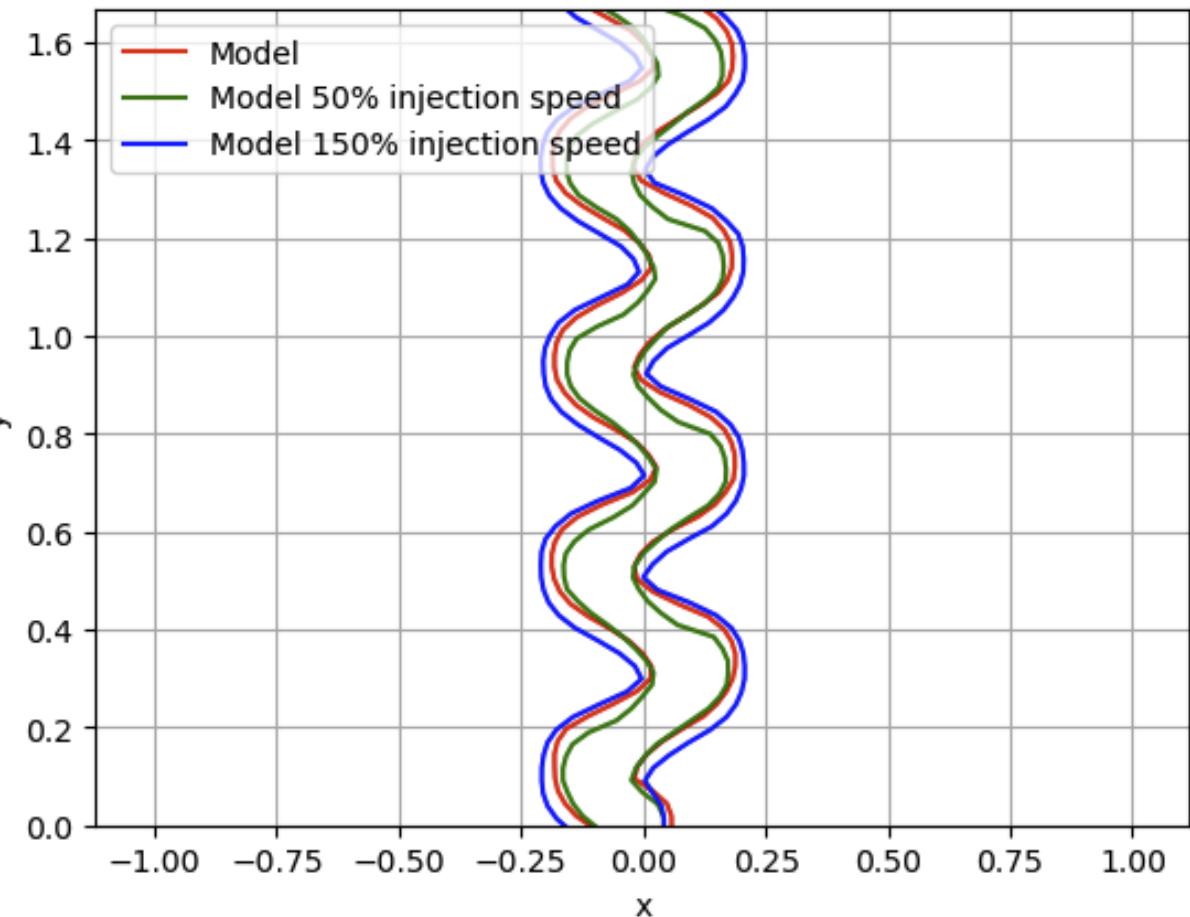
Topography (z-plane) projection



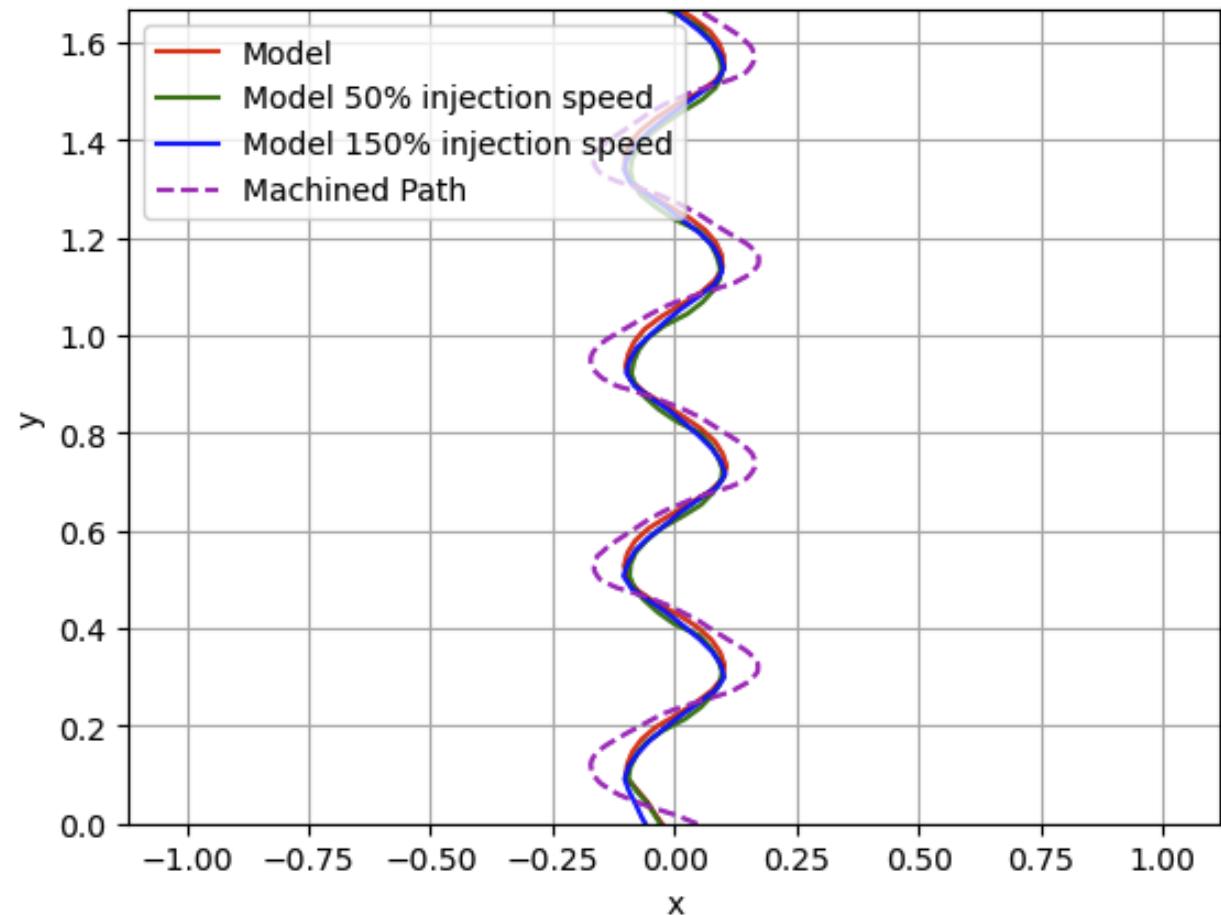
Mean path

Parameterization of injection speed

- Alter the injection speed of the material
- Decreasing the injection speed leads to a thinner sinusoidal pattern, while increasing injection speed thickens the pattern
- Injection speed does not seem to change the mean-path amplitude of the pattern

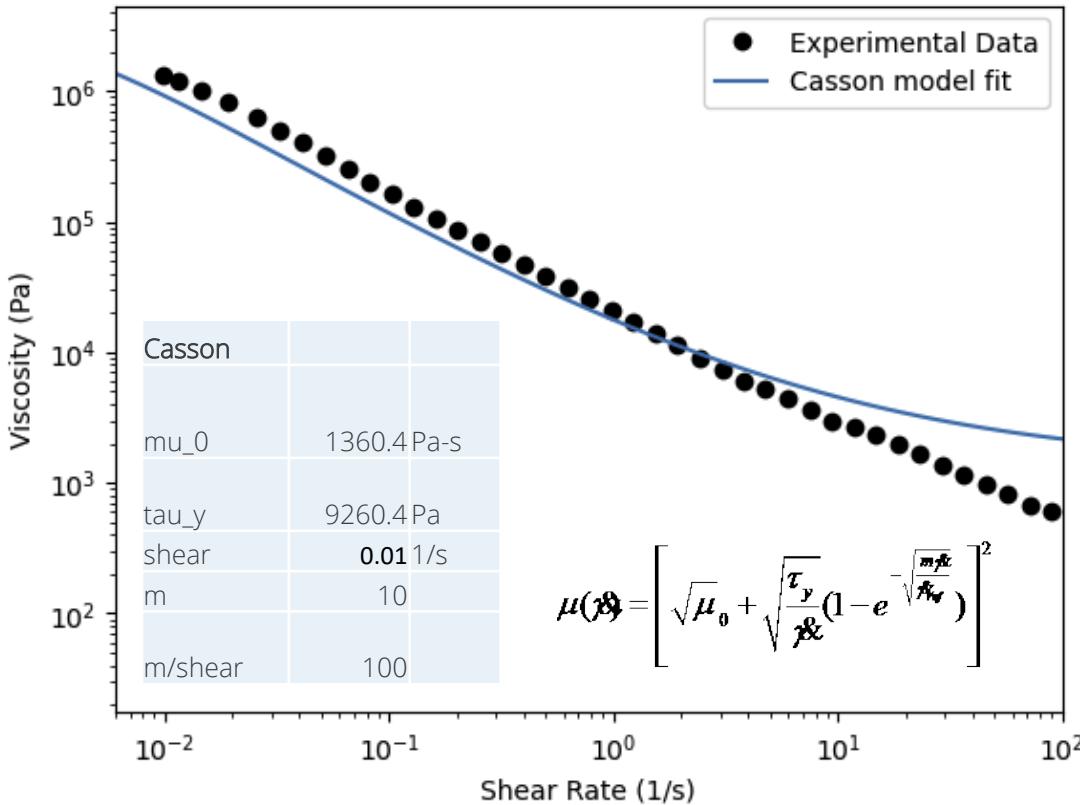


Topography (z-plane) projection

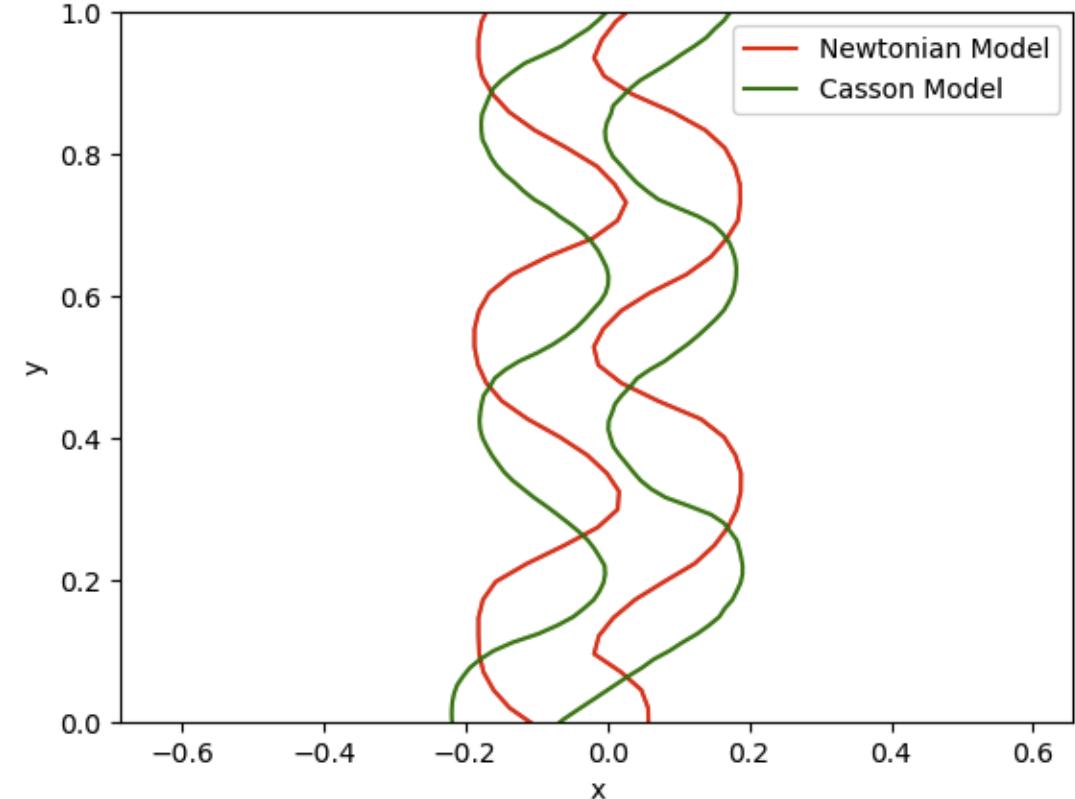


Mean path

Newtonian vs non-Newtonian (NN) model



Viscosity vs. shear rate for silicone printing material



Topography (z-plane) projection

- Fit the Casson shear-thinning viscosity model to provided experimental data for the silicone material
- Compare to Newtonian
- Phase shifted the printing pattern, but did not affect amplitude or thickness of printed pattern



Conclusions and Next Steps

- Presented a model for DIW using CDFEM to capture material interfaces
- CDFEM is a promising method for capturing material interfaces
 - Good conditioning of the resulting matrix
 - Potential issues with coarser mesh resulting in mass loss ameliorated with adaptive mesh refinement
- Bingham-Carreau-Yasuda and Casson viscosity models were used to incorporate the Non-Newtonian physics of the DIW inks material
 - Difficult to converge in 3D for fully-implicit FEM
- Other exciting Sandia work
 - Artificial Neural Nets and Computer Vision for 3D Printing
 - Digital Twin for lattice performance
- Future Work:
 - PiNNs models for experimental understanding and process control
 - NeRFs for solid model of real geometry

Incorporate elastoviscoplastic material models in work flow

